

# **INFORMATION DISCLOSURE CITATION**

(Use several sheets if necessary)

ATTY DOCKET NO.

72478-3400

SERIAL NO.

09/997,988

APPLICANT(S)

Masaki Aoki et al.

FILING DATE

November 29, 2001

GROUP

1765

## **U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## **FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

## **OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

RK		IBM Technical Disclosure Bulletin, FABRICATION PROCESS FOR GAS DISCHARGE PANELS by M. Berkenblit et al., Vol. 18, No. 6, November 1975, 2 pages
		EPITAXIAL GROWTH, Part A, edited by JW Matthews, IBM Thomas J. Watson Research Center, New York, Pages 91-99
RK		THIN FILM PROCESSES, Edited by John L. Vossen and Werner Kern, RCA Laboratories, David Sarnoff Research Center, New Jersey, 1978, Pages 340-341

EXAMINER	/Robert Kunemund/	DATE CONSIDERED	06/22/2006
----------	-------------------	-----------------	------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.